PATENT P56289

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Jong-Seo CHOI et al.

Serial No.:

to be assigned.

Examiner:

to be assigned.

Filed:

4 January 2001

Art Unit:

to be assigned.

For:

CATHODE MATERIAL FOR ELECTRON BEAM APPARATUS

INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents Washington, D.C. 20231

Sir:

In accordance with 37 C.F.R. §§1.56, 1.97, and 1.98, applicant cites, provides copies and briefly discusses the following references newly cited the Japanese search report:

U.S. Patent References:

	U.S. Patent No.	<u>Inventor</u>	<u>Issue Date</u>
1	5,519,280	Shon et al.	06/96
✓	6,124,666	Saito et al.	09/00
1	3,436,584	Hughes et al.	04/69
1	-5,982,083	Ju et al.	11/99
✓	5,072,149	Lee et al.	12/91

✓	5,580,291	Redel et al.	12/96
✓	5,977,699	Joo et al.	11/99
✓	5,808,404	Koizumi et al.	09/98
/	5,828,165	Clerc et al.	10/98

Other Foreign Patent References:

World Intellectual Property Organization

	Patent No.	<u>Inventor</u>	Issue Date
/	WO 00/21110	Choi et al.	04/00

- U.S. Patent No. 5,519,280 to Shon et al. discloses Oxide Cathode.
- U.S. Patent No. 6,124,666 to Saito et al. discloses Electron Tube Cathode.
- U.S. Patent No. 3,436,584 to Hughes et al. discloses Electron Emission Source with Sharply Defined Emitting Area.
 - U.S. Patent No. 5,982,083 to Ju et al. discloses Cathode discloses Electron Tube.
- U.S. Patent No. 5,072,149 to Lee et al. discloses Cathode discloses Electron Gun and its Manufacturing Method.
- U.S. Patent No. 5,580,291 to Redel et al. discloses Method discloses Manufacturing a Glow Cathode for an Electron Tube.
 - U.S. Patent No. 5,977,699 to Joo et al. discloses Cathode discloses Electron Tube.
- U.S. Patent No. 5,808,404 to Koizumi et al. discloses Electron Tube Including a Cathode Having an Electron Emissive Material Layer.

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U.S. Patent No. 5,828,165 to Clerc et al. discloses Thermionic Cathode discloses

Electron Tubes and Method for the Manufacture Thereof.

W.O. Patent No. 00/21110 to Choi et al. discloses Cathode Material of Electron Beam

Device and Preparation Method Thereof.

This citation of foregoing references is not intended to constitute an assertion that

Application has undertaken the search of the prior art. Accordingly, the Examiner is requested

to take a wide-ranging and through search of the relevant of art.

No fee is incurred by this Statement.

Respectfully submitted,

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Folio: P56289

Date: 10 January 2001 I.D.: REB/nb

INFORMATION DISCLOSURE STATEMENT PTO-1449 (PAGE 1 OF 1)			serial number to be	assigned.	DOCKET NO.	P56289	- 8	
			APPLICANT	Jong-Seo (CHOI et al.		75°C	
			FILING DATE 10 Janua	ry 2001	group to k	be assigned	, 9 0	
•			U.S. PATEI	NT DOCUMENTS	S			
AMINGR	DOCUMENT NUMBER	DATE		NAME	CLASS	SUBCLASS	FILING	DATE
	5,519,280	06/96	Shon et al.		313	346R		
	6,124,666	09/00	Saito et al.		313	346R		
	3,436,584	04/96	Hughes et al.		313	346		
	5,982,083	11/99	Ju et al.		313	346R		
	5,072,149	12/91	Lee et al.		313	346R		
	5,580,291	12/96	Redel et al.		445	28		
	5,977,699	11/99	Joo et al.		313	346		
	5,808,404	09/98	Koizumi et al	l	313	346R		
	5,828,165	10/98	Clerc et al.		313	346R		<u> </u>
	F	OREIGN	PATENT DO	CUMENTS			TRANS	ATION
	DOCUMENT NUMBER	DATE		COUNTRY	CLASS	SUBCLASS	YES	NO
	WO 00/21110	04/00	Europe				X	
	RU 2052855	04/93	Russian Federation				X	
	SU 616662	07/78	Former Un	ion of Soviet			X	
	OTHER DOC		<i></i>			-4 Damas	ofo l	